

Silicon Photomultipliers (SiPM), RDM-Series 1 x 16 Monolithic Array

Product Preview

ArrayRDM-0116A10-DFN

The ArrayRDM-0116A10-DFN is a monolithic 1×16 array of Silicon Photomultiplier (SiPM) pixels based on the market-leading RDM process. The RDM process has been specifically developed to create products that give high PDE at the NIR wavelengths used for LiDAR and 3D ranging applications.

In order to meet the requirements for automotive LiDAR applications, this product is intended to be qualified to the AEC-Q102 standard

An evaluation board (ArrayRDM-0116A10-GEVB) will also be available for this product.

KEY SENSOR AND PACKAGE SPECIFICATIONS

Parameter	Value	Comment
Silicon Process	RDM	
Number of Pixels	16	
Array Configuration	1 × 16	
Pixel Size	$0.17 \times 0.49 \text{ mm}$	
Pixel Pitch	0.55 mm	
Microcell Size	10 μm	
Number of Microcells per Pixel	368	
Package Size	$3 \times 12 \times 1.85 \text{ mm}$	DFN Package (W \times L \times H)
Output Type	Analog	Standard and Fast Output per Pixel

This document contains information on a product under development. **onsemi** reserves the right to change or discontinue this product without notice.

1



The ARRAYRDM-0116A10-DFN Product

ORDERING INFORMATION

See detailed ordering and shipping information in the ordering information section on page 7 of this data sheet.

BIAS PARAMETERS

Parameter	Min	Тур	Max	Unit	Comment	
Breakdown Voltage (Vbr)	_	21.7	-	V		
Over Voltage (Vov)	-	12.3	14.3	V	Typical value recommended for operation and used for	
Operating Bias (Vop)	Vop = Vbr + Vov			characterization		
Temperature Coefficient of Vbr	TBD		mV/°C			

ABSOLUTE MAXIMUM RATINGS

Parameter	Value	Unit	Comment
Maximum Bias	36 V		
Maximum Current	14	mA	For the whole array at Vop and 21°C
Maximum Storage Temperature	125	°C	
Operating Temperature Range	-40 to +105	°C	Ambient temperature

Stresses exceeding those listed in the Maximum Ratings table may damage the device. If any of these limits are exceeded, device functionality should not be assumed, damage may occur and reliability may be affected.

PACKAGE SPECIFICATIONS

Parameter	Value	Unit	Comment
ESD-HBM	TBD		
ESD-CDM	TBD		
$\theta_{\sf JC}$	4	°C/W	
θ_{JA}	245	°C/W	
MSL	3		For all part numbers

90% - 10% Recovery Time Parameter

The recovery time indicates the time taken for the microcells to recover to fully biased state. Recovery time is measured by applying a low power 905 nm 50 ps laser pulse at the SiPM and measuring the resulting pulse shape on the standard output. The 90% to 10 % recovery time is the time interval between the signal crossing the 90% threshold and

the 10% threshold, relative to the peak amplitude. Note that recovery time will depend on a number of factors including the circuit. The circuit used for this measurement is pictured in Figure 1. Typical pulse shapes for both the standard and fast output, also using this circuit, are shown in Figure 2.

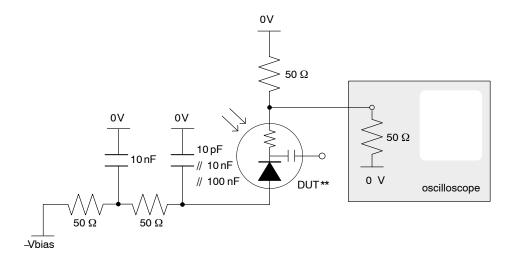


Figure 1. The Circuit used for Recovery Time Parameter Measurement

Note that any unused fast outputs should be directly connected to GND or terminated using a 50 Ω resistor to GND.

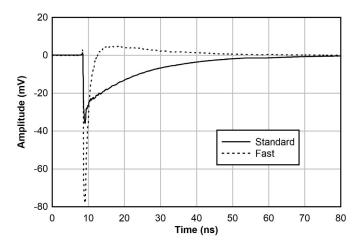


Figure 2. Pulse Shape

CONNECTION AND BOARD LAYOUT RECOMMENDATIONS

The ArrayRDM–0116A10–DFN is formed of a linear array of 16 SiPM pixels and housed in a 36–pin DFN package. Figure 3 shows the sensor array schematic. The signals from each pixel can be accessed either via the pixel cathode or fast output. The common anode is also available and allows the provision of a single bias supply for all 16 pixels. Note that any unused fast outputs should be connected to GND, or terminated using a 50 Ω resistor to GND.

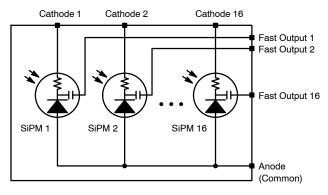


Figure 3. Array Schematic Showing Pixel Connections

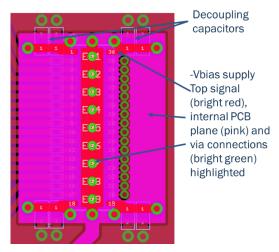


Figure 4.

The following recommendations for the bias are advised (see Figure 4):

- **onsemi** recommend the use of a negative bias supplied to the anode with cathode terminated to GND as illustrated in EVB schematic in Figure 7
- Use an internal power plane below the GND plane for the bias

- Place decoupling capacitors close to anode corner pins of the DFN (pins 1, 18, 19 & 36)
 - Pairs of 1 nF 100 V ceramic capacitors are recommended for systems where dynamic switching of bias is required
 - Higher capacitance can be used when static bias voltage is used eg 10 nF 100 V
- Use the EPAD contact to reduce the inductance of the bias supply connection to the SiPM array by using multiple plugged vias from the EPAD to the bias plane
- Decoupling capacitors should also be used on the back side of the PCB from the EPAD vias to GND when possible

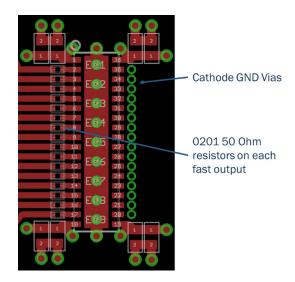


Figure 5.

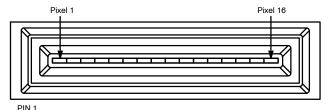
Recommendations for fast output:

- Unused fast outputs should be directly connected to GND or terminated using a 50 Ω resistor to GND. This is to avoid noise pickup and reflections from floating unterminated tracks.
- Avoid using only a capacitor to couple to fast outputs as this can lead to unwanted DC bias on the fast terminal network. At the input of the readout amplifier stage use resistive coupling to ground (50 Ω to 1 k Ω recommended) to avoid the floating condition of the fast output.
- Use series termination resistors close to the fast output pins (pins 2 to 17) of the Array (see Figure 5)
 - Helps to match the source impedance of the SiPM pixels to the PCB and amplifier load
 - Helps to reduce reflections of the high speed signals
 - 0201 package size resistors fit neatly beside each fast output pin
- GND cathodes near to each cathode pin (pins 20 to 35) using vias to GND plane when standard readout is not required

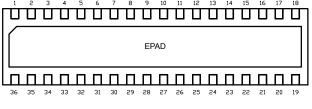
Recommendations for Signal Track Impedance:

- Match impedance of signal tracks to 50 Ω
- E.g. Use microstrip impedance where signals on the top layer of the PCB are above a ground plane on an internal layer of the PCB

PIN ASSIGNMENT



TOP VIEW



BOTTOM VIEW

Pin #	Pin Assignment	Pin Assignment Pin #		
1	Anode	19	Anode	
2	Fast output 1	20	Cathode 16	
3	Fast output 2	21	Cathode 15	
4	Fast output 3	22	Cathode 14	
5	Fast output 4	23	Cathode 13	
6	Fast output 5	24	Cathode 12	
7	Fast output 6	25	Cathode 11	
8	Fast output 7	26	Cathode 10	
9	Fast output 8	27	Cathode 9	
10	Fast output 9	28	Cathode 8	
11	Fast output 10	29	Cathode 7	
12	Fast output 11	30	Cathode 6	
13	Fast output 12	31	Cathode 5	
14	Fast output 13	32	Cathode 4	
15	Fast output 14	33	Cathode 3	
16	Fast output 15	34	Cathode 2	
17	Fast output 16	35 Cathode 1		
18	Anode	36	Anode	
EPAD	Anode			

Note that any unused fast outputs should be connected to GND or terminated via 50 Ω to GND.

EVALUATION BOARD

The ArrayRDM-0116A10-GEVB evaluation board is shown in Figure 6 and schematically (with pin outs) in Figure 7. The full drawing can be found on page 9. It consists of:

- ArrayRDM-0116A10-DFN 16-channel SiPM array
- 32 U.FL connectors for access to each pixel cathode and fast output for signal readout
- An SMA connector for applying the bias to the common anode
- Bias filtering circuit
- Decoupling capacitors (14 x 10 nF and 4 x 100 nF decoupling capacitors from anode to ground not shown)

This product allows a user to quickly and easily set up an evaluation of the array product.

Note that a negative bias supply should be supplied via the SMA connector (J33), and the U.FL connectors (J1 to J32) should be $50~\Omega$ terminated. Note that any unused fast outputs should be connected to GND or terminated using an $50~\Omega$ resistor to GND, for example with an SMA terminator.

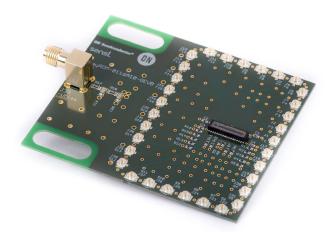
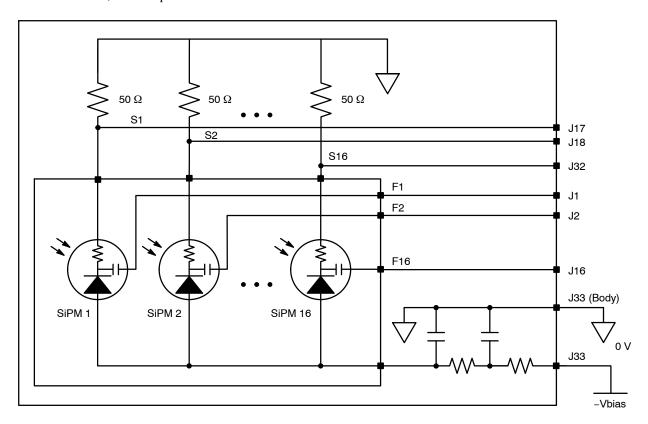


Figure 6. ArrayRDM-0116A10-GEVB Top Side View Showing the 1x16 Sensor Placement



Connector	Style
J1-J32	U.FL Receptacle (Hirose U.FL-R-SMT)
J33	SMA Jack (F)

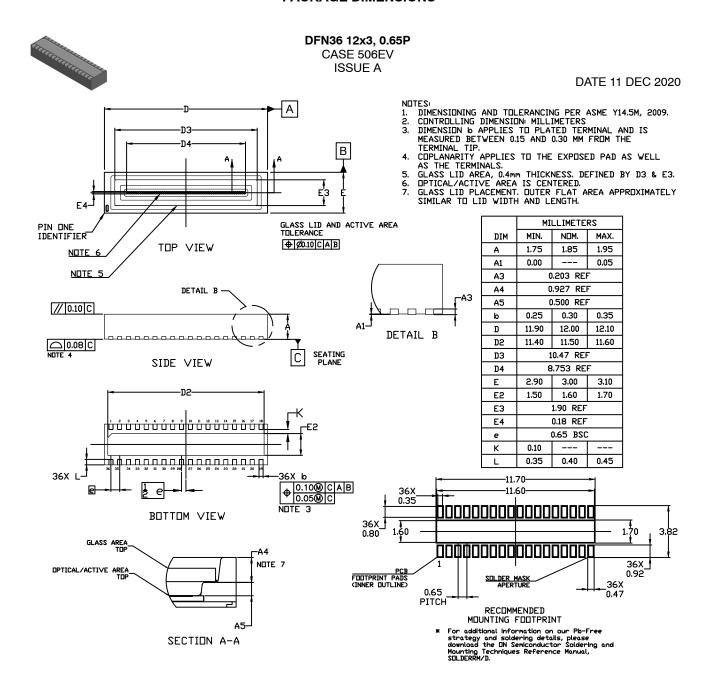
Figure 7. ArrayRDM-0116A10-GEVB Board Schematic

ORDERING INFORMATION

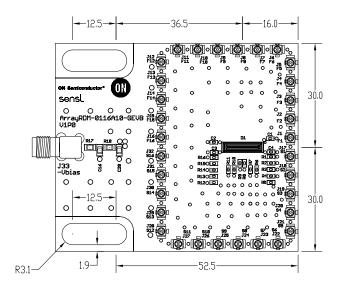
Part Number	Product Description	Shipping Format
ArrayRDM-0116A10-DFN-TR	Monolithic 1 \times 16 array of NIR sensitive SiPM pixels formed using the RDM process.	Tape and Reel
ArrayRDM-0116A10-DFN-TR1	Individual cathode and fast output connection per pixel and a common anode available via the 36-pin DFN package.	Cut Tape
ArrayRDM-0116A10-GEVB	Evaluation board consisting of an ArrayRDM-0116A10-DFN mounted onto PCB. A U.FL connector gives access to each pixel cathode and fast output. The bias is supplied via an SMA connector to the common anode.	ESD Package

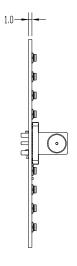
For any queries please visit https://www.onsemi.com/support/technical-support

PACKAGE DIMENSIONS



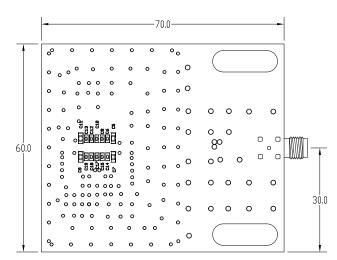
EVALUATION BOARD DIMENSIONS





Front View

Side View



Side View

Connector	Signal Name	Description	Connector	Signal Name	Description
J1	F1	Fast Output 1	J17	S1	Standard Output 1
J2	F2	Fast Output 2	J18	S2	Standard Output 2
J3	F3	Fast Output 3	J19	S3	Standard Output 3
J4	F4	Fast Output 4	J20	S4	Standard Output 4
J5	F5	Fast Output 5	J21	S5	Standard Output 5
J6	F6	Fast Output 6	J22	S6	Standard Output 6
J7	F7	Fast Output 7	J23	S7	Standard Output 7
J8	F8	Fast Output 8	J24	S8	Standard Output 8
J9	F9	Fast Output 9	J25	S9	Standard Output 9
J10	F10	Fast Output 10	J26	S10	Standard Output 10
J11	F11	Fast Output 11	J27	S11	Standard Output 11
J12	F12	Fast Output 12	J28	S12	Standard Output 12
J13	F13	Fast Output 13	J29	S13	Standard Output 13
J14	F14	Fast Output 14	J30	S14	Standard Output 14
J15	F15	Fast Output 15	J31	S15	Standard Output 15
J16	F16	Fast Output 16	J32	S16	Standard Output 16
			J33	-Vbias	Negative Bias Supply

Pinout Table

Back View

SensL is a registered trademark of Semiconductor Components Industries, LLC (SCILLC) or its subsidiaries in the United States and/or other countries. All other brand names and product names appearing in this document are registered trademarks or trademarks of their respective holders.

onsemi, ONSEMI, and other names, marks, and brands are registered and/or common law trademarks of Semiconductor Components Industries, LLC dba "onsemi" or its affiliates and/or subsidiaries in the United States and/or other countries. onsemi owns the rights to a number of patents, trademarks, copyrights, trade secrets, and other intellectual property. A listing of onsemi's product/patent coverage may be accessed at www.onsemi.com/site/pdf/Patent-Marking.pdf. Onsemi reserves the right to make changes at any time to any products or information herein, without notice. The information herein is provided "as-is" and onsemi makes no warranty, representation or guarantee regarding the accuracy of the information, product features, availability, functionality, or suitability of its products for any particular purpose, nor does onsemi assume any liability arising out of the application or use of any product or circuit, and specifically disclaims any and all liability, including without limitation special, consequential or incidental damages. Buyer is responsible for its products and applications using onsemi products, including compliance with all laws, regulations and safety requirements or standards, regardless of any support or applications provided by onsemi. "Typical" parameters which may be provided in onsemi data sheets and/or specifications can and do vary in different applications and actual performance may vary over time. All operating parameters, including "Typicals" must be validated for each customer application by customer's technical experts. onsemi does not convey any license under any of its intellectual property rights nor the rights of others. onsemi products are not designed, intended, or authorized for use as a critical component in life support systems or any EDA class 3 medical devices or medical devices with a same or similar classification in a foreign jurisdiction or any devices intended for implantation in the human body. Should Buyer pu

PUBLICATION ORDERING INFORMATION

LITERATURE FULFILLMENT:
Email Requests to: orderlit@onsemi.com

onsemi Website: www.onsemi.com

TECHNICAL SUPPORT North American Technical Support: Voice Mail: 1 800-282-9855 Toll Free USA/Canada Phone: 011 421 33 790 2910

Europe, Middle East and Africa Technical Support:

Phone: 00421 33 790 2910

For additional information, please contact your local Sales Representative